Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the

application:

Listing of Claims:

1. (Currently Amended) A dielectric material for forming a structure of an integrated circuit, said

dielectric material comprising a plurality of <u>fluorinated</u> carbon nanostructures.

2. (Cancelled)

3. (Currently Amended) The dielectric material of claim 1 wherein said fluorinated carbon

nanostructures comprise a plurality of fluorinated carbon nanotubes.

4. (Original) The dielectric material of claim 1 wherein said dielectric material has a dielectric

constant of less than about 3.

5. (Original) The dielectric material of claim 1 wherein said structure further comprises at least

one conductive feature disposed in said dielectric material.

6. (Currently Amended) The dielectric material of claim 1 wherein said <u>fluorinated</u> carbon

nanostructures comprise a plurality of fluorinated carbon buckyballs.

7. (Original) The dielectric material of claim 1 further comprising a cap layer on said dielectric

material.

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- 8. (Currently Amended) The dielectric material of claim 7 wherein said <u>fluorinated</u> carbon nanotubes <u>nanostructures</u> and said cap layer have an effective dielectric constant of less than about 3.
- 9. (Currently Amended) The dielectric material of claim 1 further comprising:
 a copolymer layer binding said <u>fluorinated</u> carbon nanotubes <u>nanostructures</u> to define the dielectric material.
- 10. (Currently Amended) The dielectric material of claim 7 wherein said <u>fluorinated</u> carbon nanotubes <u>nanostructures</u> and said copolymer layer have an effective dielectric constant of less than about 3.
- 11. (Currently Amended) A semiconductor structure formed on a substrate, comprising:

 a dielectric layer comprising a plurality of <u>fluorinated</u> carbon nanostructures; and

 at least one conductive feature in said dielectric layer, said conductive feature electrically
 isolated from nearby conductive features by portions of said dielectric layer.
- 12. (Original) The semiconductor structure of claim 11 wherein said dielectric layer has an exposed surface, and further comprising:

a cap layer of an insulating material at least partially covering said exposed surface, said cap layer having a top surface, and said conductive feature having a top surface substantially coplanar with said top surface of said cap layer.

- 13. (Cancelled)
- 14. (Currently Amended) The semiconductor structure of claim 11 wherein said <u>fluorinated</u> carbon nanostructures comprise a plurality of fluorinated carbon nanotubes.

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15. (Original) The semiconductor structure of claim 11 wherein said dielectric layer has a dielectric constant of less than about 3.

- 16. (Original) The semiconductor structure of claim 11 wherein said structure comprises a plurality of conductors electrically isolated by said layer of said dielectric material.
- 17. (Currently Amended) The semiconductor structure of claim 11 wherein said <u>fluorinated</u> carbon nanostructures comprise a plurality of fluorinated carbon buckyballs.
- 18. (Currently Amended) The semiconductor structure of claim 11 further comprising: a cap layer disposed on said <u>fluorinated</u> carbon nanostructures.
- 19. (Currently Amended) The semiconductor structure of claim 18 wherein said <u>fluorinated</u> carbon nanostructures and said cap layer collectively have a dielectric constant of less than about 3.
- 20. (Original) The semiconductor structure of claim 11 further comprising:
 a substrate selected from the group consisting of an interconnect level, a dielectric material, a buried barrier layer, a metallization line, and a semiconductor wafer.
- 21. (Original) An integrated circuit comprising a plurality of circuit elements and the semiconductor structure of claim 11, said conductive feature being electrically coupled with at least one of said circuit elements.
- 22. (Currently Amended) The dielectric material of claim 11 further comprising:
 a copolymer layer binding said <u>fluorinated</u> carbon nanotubes <u>nanostructures</u> to define said dielectric layer.

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23. (Currently Amended) The dielectric material of claim 22 wherein said <u>fluorinated</u> carbon nanotubes <u>nanostructures</u> and said copolymer layer have an effective dielectric constant of less than about 3.

24-45. (Cancelled)

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